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Introduction

This year in Beijing, China, we held the sixth conference of Optical Systems and Modern Optoelectronic Instruments, which has been a sub-conference of OIT since its inauguration in 2008. In 2017, we selected 23 oral presentations from over 80 submissions to this sub-conference, including 8 invited talks. Experts from Japan, the Netherlands, the Islamic Republic of Iran and China attended the sub-conference in the Beijing International Conference Center, and presented their latest research findings. We also had an excellent attentive audience who provided many good questions and stimulated exchanges with the speakers.

There were five sessions in the sub-conference of Optical Systems and Modern Optoelectronic Instruments: Digital Holography (session 1), Computational Imaging and Post-Processing (session 2), Opto-Mechanics and Instruments (session 3), Optical System Design (session 4) and Optical Testing (session 5).

We believe that this year's Optical Systems and Modern Optoelectronic Instruments conference maintained its previous high standards, and we hope that the papers included in the proceedings will prove valuable to our fellow scientists and engineers.

Yongtian Wang
Baohua Jia
Kimio Tatsuno

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